

Notice of References Cited	Application/Control No. 10/696,882	Applicant(s)/Patent Under Reexamination BADER ET AL.	
	Examiner G. Nagesh Rao	Art Unit 1722	Page 1 of 1

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	A	US-6,242,764	06-2001	Ohba et al.	257/190
*	B	US-2003/0057434	03-2003	HATA et al.	257/103
*	C	US-6,927,155	08-2005	Lugauer et al.	438/604
*	D	US-6,730,939	05-2004	Eisert et al.	257/98
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	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
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NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Mayer et al, Electronic Materials Science: For Integrated Circuits in Si and GaAs, MacMillan Publishing, 1990, Page 433.
	V	Wikipedia entry on Metalorganic Vapour Phase Deposition.
	W	
	X	

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.